

L Number	Hits	Search Text	DB	Time stamp
100	4	((("5686504") or ("6358606") or ("6224949") or ("5288827"))).PN.	USPAT; US-PGPUB	2004/06/25 13:56
101	78566	semiconductor same wafer	USPAT; US-PGPUB	2004/06/25 14:43
102	0	((("5686504") or ("6358606") or ("6224949") or ("5288827"))).PN.) and (semiconductor same wafer)	USPAT; US-PGPUB	2004/06/25 13:57
103	0	semiconductor and ((("5686504") or ("6358606") or ("6224949") or ("5288827"))).PN.)	USPAT; US-PGPUB	2004/06/25 13:57
104	0	wafer and ((("5686504") or ("6358606") or ("6224949") or ("5288827"))).PN.)	USPAT; US-PGPUB	2004/06/25 13:58
105	27626	pressure adj sensitive adj adhesive	USPAT; US-PGPUB	2004/06/25 14:44
106	16588	photoinitiator photoinitiators photopolymerization adj (initiator initiators)	USPAT; US-PGPUB	2004/06/25 14:44
107	488	(semiconductor same wafer) and (pressure adj sensitive adj adhesive)	USPAT; US-PGPUB	2004/06/25 13:59
108	87	((semiconductor same wafer) and (pressure adj sensitive adj adhesive)) and (photoinitiator photoinitiators photopolymerization adj (initiator initiators))	USPAT; US-PGPUB	2004/06/25 13:59
109	652	molar adj (adsorptivity absorption)	USPAT; US-PGPUB	2004/06/25 14:00
110	16	(photoinitiator photoinitiators photopolymerization adj (initiator initiators)) same (molar adj (adsorptivity absorption))	USPAT; US-PGPUB	2004/06/25 14:00
111	0	((photoinitiator photoinitiators photopolymerization adj (initiator initiators)) same (molar adj (adsorptivity absorption))) and ((semiconductor same wafer) and (pressure adj sensitive adj adhesive))	USPAT; US-PGPUB	2004/06/25 14:00
112	82	maximum adj (adsorptivity absorption) same (photoinitiator photoinitiators photopolymerization adj (initiator initiators))	USPAT; US-PGPUB	2004/06/25 14:01
113	2	(maximum adj (adsorptivity absorption) same (photoinitiator photoinitiators photopolymerization adj (initiator initiators))) and ((semiconductor same wafer) and (pressure adj sensitive adj adhesive))	USPAT; US-PGPUB	2004/06/25 14:01
114	2	(maximum adj (adsorptivity absorption) same (photoinitiator photoinitiators photopolymerization adj (initiator initiators))) and (semiconductor same wafer)	USPAT; US-PGPUB	2004/06/25 14:02
115	0	((photoinitiator photoinitiators photopolymerization adj (initiator initiators)) same (molar adj (adsorptivity absorption))) and (semiconductor same wafer)	USPAT; US-PGPUB	2004/06/25 14:02
116	0	((semiconductor same wafer) and (pressure adj sensitive adj adhesive)) and (photoinitiator photoinitiators photopolymerization adj (initiator initiators))) and (molar adj (adsorptivity absorption))	USPAT; US-PGPUB	2004/06/25 14:02

117	2	((semiconductor same wafer) and (pressure adj sensitive adj adhesive)) and (photoinitiator photoinitiators photopolymerization adj (initiator initiators))) and (maximum adj (adsorptivity absorption) same (photoinitiator photoinitiators photopolymerization adj (initiator initiators)))	USPAT; US-PGPUB	2004/06/25 14:03
118	9911	\$phosphine adj oxide	USPAT; US-PGPUB	2004/06/25 14:04
119	202	morpholinophenyl same photoinitiator	USPAT; US-PGPUB	2004/06/25 14:04
120	301	morpholino same photoinitiator	USPAT; US-PGPUB	2004/06/25 14:04
121	25	((semiconductor same wafer) and (pressure adj sensitive adj adhesive)) and (\$phosphine adj oxide)	USPAT; US-PGPUB	2004/06/25 14:04
122	2	((semiconductor same wafer) and (pressure adj sensitive adj adhesive)) and (morpholinophenyl same photoinitiator)	USPAT; US-PGPUB	2004/06/25 14:04
123	1	((semiconductor same wafer) and (pressure adj sensitive adj adhesive)) and (morpholino same photoinitiator)	USPAT; US-PGPUB	2004/06/25 14:04
124	50149	(second same wavelength and first same wavelength) (second adj wavelength and first adj wavelength) (second adj wavelength same first adj wavelength)	USPAT; US-PGPUB	2004/06/25 14:05
125	25	((semiconductor same wafer) and (pressure adj sensitive adj adhesive)) and (\$phosphine adj oxide)) (((semiconductor same wafer) and (pressure adj sensitive adj adhesive)) and (morpholinophenyl same photoinitiator)) (((semiconductor same wafer) and (pressure adj sensitive adj adhesive)) and (morpholino same photoinitiator))	USPAT; US-PGPUB	2004/06/25 14:05
126	89371	semiconductor same wafer	EPO; JPO; DERWENT	2004/06/25 14:44
127	22055	pressure adj sensitive adj adhesive	EPO; JPO; DERWENT	2004/06/25 14:44
128	13637	photoinitiator photoinitiators photopolymerization adj (initiator initiators)	EPO; JPO; DERWENT	2004/06/25 14:44
129	0	(clearcoat same (automobile automotive vehicle)) and ((topcoat topcoats) same (automobile automotive vehicle)) and ((clearcoat same (automobile automotive vehicle)) and ((sag drip run) near resistance))	EPO; JPO; DERWENT	2004/06/25 14:45
130	0	((topcoat topcoats) same (automobile automotive vehicle)) and ((clearcoat same (automobile automotive vehicle)) and ((sag drip run) near resistance))	EPO; JPO; DERWENT	2004/06/25 14:45
131	0	((topcoat topcoats) same (automobile automotive vehicle)) and (clearcoat same (automobile automotive vehicle))	EPO; JPO; DERWENT	2004/06/25 14:45
132	0	((topcoat topcoats) same (automobile automotive vehicle)) and wafer	EPO; JPO; DERWENT	2004/06/25 14:45
133	5237	adhesive and wafer	EPO; JPO; DERWENT	2004/06/25 14:45
134	19	(semiconductor same wafer) and (pressure adj sensitive adj adhesive) and (photoinitiator photoinitiators photopolymerization adj (initiator initiators))	EPO; JPO; DERWENT	2004/06/25 14:53
135	1	("5384007").PN.	USPAT; US-PGPUB	2004/06/25 14:54